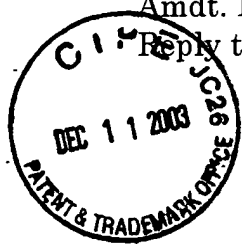


Appl. No. 10/008,958  
Amdt. Dated December 8, 2003  
Reply to Office Action of September 8, 2003

Attorney Docket No. 81790.0227  
Customer No. 26021



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:  
Miki SASAKI, et al.  
Serial No.: 10/008,958  
Confirmation No.: 5427  
Filed: December 5, 2001  
For: SEMICONDUCTOR DEVICE  
INCORPORATING A DICING  
TECHNIQUE FOR WAFER  
SEPARATION AND A METHOD FOR  
MANUFACTURING THE SAME (As  
Amended)

Art Unit: 2814

Examiner: Nathan W. Ha

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December 8, 2003

Date of Deposit

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Name

Signature

12/08/03

Date

**AMENDMENT UNDER 37 C.F.R. § 1.116**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action dated September 8, 2003, please amend  
the above-referenced application as follows:

**Amendments** to the Claims are reflected in the Listing of Claims, which  
begins on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.

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